École de simulation de détecteurs silicium LPNHE - Paris du 15 au 17 septembre 2014

Simulations des senseurs à pixel avec Silvaco

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Outline

- Introduction & motivations
- Pixels for high luminosity colliders
- Selected results
 - Edgeless sensors
 - Radiation damage models
 - Electric field measurement
- Comments and conclusions



INTRODUCTION & MOTIVATIONS

Normal work flow for a HEP silicon sensors



TCAD simulation work flow



So why bother with simulations?

• You repeat all the "steps" of real sensors...

So why bother with simulations?

- You repeat all the "steps" of real sensors...
- It is not true!

Possible work flow for real sensors



TCAD simulation work flow



TCAD simulation work flow



- Simulating sensors helps in saving:
- Development time
- ➢ Number of submissions
- Money
- You can learn a lot in terms of:

Physics

• Study quantities otherwise not accessible!

TCAD simulation work flow







PIXELS FOR HIGH LUMINOSITY COLLIDERS

The ATLAS experiment



The ATLAS Inner Detector



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The ATLAS pixel detector



ATLAS Pixel Module

- 16 front-end chips (FE-I3) module with a Module Controller Chip (MCC)
- 46080 R/O channels 50 μm x 400 μm (50 μm x 600 μm for edge pixel columns between neighbour FE-I3 chips)
- Planar n-in-n DOFZ silicon sensors, 250um tick
- Designed for 1 x 10¹⁵ 1MeV fluence and 50 Mrad
- Optolink R/O: 40÷80 Mb/link

IPRD10, Siena 9.6.2010 - Alessandro La Rosa (CERN)

- ATLAS Pixel Detector
 - 3 barrels + 3 forward/backwarc disks
 - 112 stave and 4 sectors
 - 1744 modules
 - 80 million channels



The Atlas Pixel sensors



LHC & ATLAS upgrades for the High Lumi era



Veutral had. >100keV Sum Foreseen Tracker Upgrades Fluence (particles/cm2) 51+a1 1e+15-2030: Particle fluence LS1: new Insertable pixel B-layer (IBL) (LS2: Fast Tracking (FTK)) **Pixels** Strips 1e+13-LS3: All new Tracking Detector 20 40 80 100 120 60 Radius (cm)

LHC & ATLAS upgrades for the High Lumi era



Pixels for the future LHC experiments

- Thin: reduce the material budget, cope with charge trapping
- Cheap: large area to be instrumented O(10 m²)
- Efficient: very limited module tiling in the innermost layers



SLIM EDGE DETECTORS



 Table 6.6: Inner tracker active area and channel count.

SELECTED RESULTS

EDGELESS SENSORS

Edgeless pixels via Deep Reactive Ion Etching

- Joint FBK-LPNHE project
- Goal: make the border a damage free ohmic contact
- How: DRIE
- Target: intermediate layers
- 200 μm thick n-on-p production
 - 500 µm support wafer
 - Polarization via bias tab
- Pixel-to-trench distance as low as 100 μm



Edgeless designs



A concrete example: Active Edge sensors



Intermezzo: TCAD inputs

• To get reliable predictions you need precise inputs; *e.g.* doping profiles via SIMS



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IV on test structures

SIMULATIONS

Crucial parameters: p-spray implant characteristics

DATA



BD Voltage: Agreement within 20% or better

Charge collection efficiency with MIP

 We can profit of SEU module to study the drift of charge released along a track



Response to a MIP

Expected Initial current ~ λ (<v_e>+<v_h>) = 3.9x10⁻⁷ A



Charge collection efficiency studies (CCE)



Signal at 50 V for unirradiated sensors (zoom)



RADIATION DAMAGE MODELS

Radiation damage: data vs simulations



Radiation damage effects

• Implement radiation damage effects via traps in the forbidden gap $N = \eta \times \phi$

Type	Energy (eV)	$\sigma_e({ m cm}^2)$	$\sigma_h({ m cm}^2)$	$\eta({\rm cm}^{-1})$
А	E_{C} -0.42	$9.5 imes10^{-15}$	9.5×10^{-14}	1.613
А	E_{C} -0.46	$5.0 imes 10^{-15}$	$5.0 imes 10^{-14}$	0.9
D	$E_V + 0.36$	$3.23 imes 10^{-13}$	$3.23 imes 10^{-14}$	0.9 (1)



"Simulations of radiation-damaged 3D detectors for the Super-LHC",

D. Pennicard et al., Nucl. Instrum. and Meth. A 592 (2008) 16-25

ATLAS: an example for radiation damage

ATLAS> trap acceptor e.level=0.495 density=1e+13 degen=1 sign=1e-15 sigp=1e-15 Mesh Type: non-cylindrical **Carriers** traps Total grid points: 37668 Total triangles : 74496 Obtuse triangles : 0 (0 %) ATLAS> trap donor e.level=0.48 density=1e+13 degen=1 sign=1e-15 sigp=1e-15 ATLAS> ## else ATLAS> ATLAS> ## if.end ATLAS> ATLAS> ## if.end ATLAS> ATLAS> ATLAS> # MODELS, IMPACT, INTERFACE & METHOD ATLAS> models bipolar temperature=290 print ATLAS> impact selb ATLAS> ATLAS> interface Of=3e+12 x.min=1 Interface models ATLAS> interface Qf=3e+12 x.max=1 ATLAS> interface S.N=5 S.P=5 ATLAS> ATLAS> ATLAS> ### altering default recombination lifetime for bulk ATLAS> MATERIAL region=2 TAUP0=7.80896e-08 TAUN0=9.43913e-08 ETRAP=0.09 ATLAS> ATLAS> method gummel newton climit=1e-5

Depletion voltage – data vs simulations



Silicon/SiO₂ interface defects

- Ionizing energy loss in the oxide creates defects at the Surface:
- Increase in interface/oxide charge
- Defects at the interface silicon oxide

Type	$E_C - E_{it} (eV)$	$\sigma_e(\mathrm{cm}^2)$	$\sigma_h({ m cm}^2)$	$N(10^{11} {\rm cm}^{-2})$
A	0.391	1.2×10^{-15}	1.2×10^{-15}	10
\mathbf{A}	0.598	$6.0 imes 10^{-16}$	$6.0 imes 10^{-16}$	5
\mathbf{A}	0.462	$2.5 imes 10^{-17}$	2.5×10^{-17}	₅ (2)



"Study of surface radiation damage in silicon sensors", J. Zhang, 18th RD50 Workshop, Liverpool, 23-25/5/2011

Leakage current – data vs simulations



Charge collection efficiency studies (CCE)



Charge collection efficiency studies (CCE)



ELECTRIC FIELD MEASUREMENT

Grazing angle technique

 Technique developed by Henrich, Bertl, Gabathuler & Horisberger (<u>CMS note 1997/021</u>)



- Tracks enter at shallow angle wrt to the detector surface
- Charge collection efficiency as a function of the bulk depth
 - (Analog readout)

Extract electric field from TCAD sims & tb data



Fig. 2

THE GRAZING ANGLE TECHNIQUE FOR DETERMINING CHARGE COLLECTION PROFILES. THE CLUSTER LENGTH IS PROPORTIONAL TO THE

DEPTH OVER WHICH CHARGE IS COLLECTED.

Study of Charge Collection as a function of charge deposition depth
Parameterization of the Electric Filed in simulations
Comparison data/simulation



Fig. 10

The measured charge collection profiles at bias voltages of 150 V, 200 V, 300 V, and 450 V are shown as solid dots for fluences of $6 \times 10^{14} \text{ N}_{eq}/\text{cm}^2$. The BF simulation is shown as the solid histogram in each plot.

Level of detail attained: DP effect



- They vary the input parameters of the model to reproduce the profiles they observe in data
- Max fluence investigated: 6x10¹⁴ n_{eq}/cm²
- Time to look at high fluences!

Project: RD50 testbeam



•1 week of beamtime at CERN SpS (120 GeV/c π)
•DUTs: Highly irradiated pixels
•TCAD simulations for different radiation damage models

Possible measurements

- Irradiation fluences: 1÷6x10¹⁵ n_{eq}/cm²
- Different geometries (strips and pixels)
- Different materials (DOFZ vs MCz), type (n vs p)
- Different radiations (n, p, π)
- Charge multiplication? (Dream: only if $\sigma_{trk} \sim 1 \mu m$)

Simulated structure



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Collected charge vs track entry point



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Scanning the bulk depth



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Scanning the bulk depth



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Ionizing particles and carrier distributions



Carrier distribution during the particle strike

Ionizing particles and carrier distributions



• Carrier distribution 1 s after the particle strike

Radiation damage model I - Pennicard



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Charge profile for Pennicard model



Radiation damage model II - Chiochia



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Charge profile for Chiochia model



COMMENTS AND CONCLUSIONS

TCAD simulations for HEP sensors: my view

- Thanks to TCAD you can make powerful predictions on new sensors
- TCAD could save you money and time
- ... but to learn it and produce reliable results might take some time
- Better to have a good knowledge of semiconductor physics before using TCAD

TCAD simulations: time needed

- The CPU time increases with number of meshing points
- E.g. : 1 minute per bias point for ~ 100k nodes mesh on a 8 core 3GHz machine
- For irradiated sensors it took me ~ 1/2 week to get full depletion
- Another example: time-domain solution. For the same structure above you need to solve for ~ 10 ns in time steps of ps, with ~ 1 minute per point
 → it took me 1÷2 days

> Look for optimizations & compromises!

Conclusions

- TCAD is a very powerful tool for HEP silicon sensors
- You can reduce the number of submission, and so cutting time and money to get results
- The program is rather complex, and if you don't know what you are doing is easy to get a bit lost
- So, if you want to use TCAD, it is recommended to have a good knowledge of semiconductor physics, and good data inputs

One last thing

- It could be <u>nice</u> and <u>funny</u> to work with TCAD simulations ⁽ⁱ⁾
- So if you are interested in working with TCAD simulations, feel free to contact me: <u>marco.bomben@cern.ch</u>





BACKUP MATERIAL

Before strike

Electrons



30 ps after particle hit

Electrons



80 ps after particle hit

Electrons



780 ps after particle hit

Electrons



4 ns after particle hit

Electrons



100 ns after particle hit

Electrons



Digitizer inputs from TCAD: ramo potential



Simulation of CCE studies with laser

